

INFORMATION DISCLOSURE CITATION

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ATTY DOCKET NO.

118/02339

SERIAL NO.

U.S. Nat'l of PCT/IL99/0488

APPLICANT(S)

Amichai HEINES, et al.

09/914894

FILING DATE

Herewith

GROUP

To be assigned

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AA	1	5,534,888	9 Jul '96	LEBBY, M. S. et al.			
AA	2	5,867,202	2 Feb '99	KNIPE, R. L. et al.			
AA	3	4,288,788	8 Sep '81	ROGERS, W. A. et al.			
AA	4	5,636,052	3 Jun '97	ARNEY, S. C. et al.			
AA	5	5,841,579	24 Nov '98	BLOOM, D. M. et al.			
AA	6	5,447,600	5 Sep '95	WEBB, D. A.			
AA	7	5,768,007	16 Jun '98	KNIPE, R. et al.			
AA	8	5,867,302	2 Feb '99	FLEMING, J. G.			
AA	9	5,535,047	9 Jul '96	HORNBECK, L. J.			
AA	10	5,465,401	7 Nov '95	THOMPSON, E. E.			
AA	11	3,916,403	28 Oct '75	MANDZSU, J. et al.			

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
AA	12	DE 195 45 255	28 May '97	Germany				
AA	13	DE 195 26 656	23 Jan '97	Germany				
AA	14	EP 0 262 829	6 Apr '88	Europe				
AA	15	EP 0 521 713	7 Jan '93	Europe				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

AA	16	De BOER, M. P. et al.; "Adhesion of Polysilicon Microbeams in Controlled Humidity Ambients;" pp. 131-136; Mat. Res. Soc. Symp. Proc.; Vol. 518						
AA	17	TAS, N. et al.; "Stiction in Surface Micromachining;" 1996; pp. 385-397; J. Micromech. Microeng.; Vol. 6						

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11/05/03

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Am	18	4,825,205	25 Apr '89	LEE, G. S.			
Am	19	4,775,863	4 Oct '88	JÁKI, L. et al.			
Am	20	5,475,939	19 Dec '95	SALAM, H. P. A.			
Am	21	4,163,332	7 Aug '79	SALAM, H. P. A.			
Am	22	5,185,600	9 Feb '93	SALAM, H. P. A.			
Am	23	4,819,357	11 Apr '89	SALAM, H. P. A.			
Am	24	3,562,938	16 Feb '71	SALAM, H. P. A.			
Am	25	4,063,377	20 Dec '77	HUKILL, M. E.			
Am	26	4,597,209	1 Jul '86	HUKILL, M. E.			
Am	27	567,379	8 Sep 1896	DALUMI, J. A.			
Am	28	4,389,804	28 Jun '83	SEIBERT, L. et al.			

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							YES	NO

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Am	29	FLYNN, A. M. et al.; "Piezoelectric Micromotors for Microrobots;" March 1992; pp.44-51; Journal of Microelectromechanical Systems; Vol. 1; No. 1					
Am	30	TANG, W. C. et al.; "Electrostatic Comb Drive Levitation and Control Method;" December 1992; pp. 170-178; Journal of Microelectromechanical Systems; Vol. 1; No. 4					

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AA	31	3,365,824	30 Jan '68	WINROW, D.			

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							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

AA	32	GUCKEL; "Fabrication of Micromechanical Devices for Polysilicon Films with Smooth Surfaces;" 1989; pp. 117-122; Sensors and Actuators; Vol. 20
AA	33	De BOER, M. P. et al.; "Measuring and Modeling Electrostatic Adhesion in Micromachines;" Sandia National Labs; Albuquerque, NM; 87185-1413

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